



EC  
11-101  
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :  
Masamichi NAKASHIBA et al. : Docket No. 2000\_0722  
Serial No. 09/589,388 : Group Art Unit 3723  
Filed June 8, 2000 : Examiner G. Nguyen

APPARATUS FOR AND METHOD FOR  
POLISHING WORKPIECE

THIS DOCUMENT IS AUTOMATICALLY  
CLASSIFIED IN THE  
CLASS NO. 25-0975.

**SUPPLEMENTAL AMENDMENT**

Assistant Commissioner for Patents,  
Washington, D.C.

Sir:

Further to the Amendment filed September 21, 2001, kindly amend the application  
as follows:

**IN THE CLAIMS:**

Kindly amend claim 76 as follows:

76. (Amended) A polishing apparatus according to claim 73, wherein said central  
area and said outer circumferential area are formed by chambers formed in said top ring.

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